



**NATIONAL INSTITUTE OF TECHNOLOGY
ROURKELA – 769 008(ODISHA)
SPONSORED RESEARCH, INDUSTRIAL CONSULTANCY & CONTINUING
EDUCATION**

ADVERTISEMENT NO:NITR/SR/2013/PH-SDF/47Dated: 25.10.2013

Applications are invited on prescribed format available in http://www.nitrkl.ac.in/Jobs_Tenders/5ProjectFellowships/Default.aspx for the following assignment in a purely time bound research project to carry out research work, experiments and analysis in the Department of Life Science of the Institute.

1. Name of the Temporary Post : Junior Research Fellow (JRF)
2. Name of the Research Project : **“ Sputter growth of high-k dielectric thin films and nanostructures on silicon substrates for microelectronic and sensor applications”**
3. Name of the Sponsoring Agency : SERB, Department of Science and Technology (DST), Govt. of India
4. Tenure of the Project : 03 Years
5. Tenure of the Assignment : 03 Years
6. Job Description : Research work
7. Consolidated monthly compensation / Fellowship : Rs. 16,000/- P.M. for first two years and Rs.18,000/- P.M. for third year
8. Essential Qualifications and experience : M.Sc. or M. Tech in Physics or Materials science with at least 65 % marks in master degree
9. Desirable Qualifications/ Experiences : NET/ GATE qualified, 1st class throughout the career
Experience in experimental condensed matter physics.
10. Accommodation : Bachelor accommodation in the Institute may be provided subject to availability.

(P.T.O)

11. For technical information on the project, the candidate may contact the Principal Investigator at the following address:

Name : Dr. JyotiPrakashKar
Address : Department of Physics
N.I.T., Rourkela-769 008
Telephone No : 09438532157
E-mail : karjp@nitrkl.ac.in

Eligible candidates may apply in the prescribed format (http://www.nitrkl.ac.in/Jobs_Tenders/5ProjectFellowships/Default.aspx) affixed with coloured photographs to be submitted in duplicate along with photo copies of relevant certificates, grade/mark sheets, publications etc., to **Asst. Registrar, SRICCE, National Institute of Technology, Rourkela-769 008** on or **before 15.11.2013**. The cover should be super-scribed clearly the post applied for & Name of the Project.

Mere possession of minimum qualification does not guarantee invitation to the interview. Candidates will be short listed based on merit and need of the project.

Asst. Registrar (SRICCE)

Copy to : 1) All Heads of the Departments, NIT, Rourkela for publication on Departmental Notice Boards.
2) Dr. J. P. Kar, Principal Investigator with a request to give wide publicity to advertisement.
3) Head of the Department, PH
5) Project file.